INFORMATION DISCLOSURE STATEMENT BY APPLICANT Substitute for form PTO-1449 Sheet 1 of 1 U.S. PATENT DOCUMENTS				Application Number Filling Date First Namod Inventor Art Unit Examiner Name Attorney Docket Number		10/799,073 12 March 2004 Michel Luc Cote 1756 Stephen B. Rosasco NMTI 1002-26			
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Complete if Known Substitute for form 1449/PTO Application Number 10/799,073 Filing Date 12 March 2004 INFORMATION DISCLOSURE First Named Inventor Michel Luc Cole STATEMENT BY APPLICANT Art Unit 1756 (Use as many sheets as necessary) Examiner Name Unassigned Sheet 1 Attorney Dockot Number NMTI 1002-26 of 1 U. S. PATENT DOCUMENTS Name of Patentee or Applicant of Cited Document Cile No. **Document Number** Publication Date ages, Columns, Lines, Where Initials* MM-DD-YYYY Roceant Passages or Relevant Number-Kind Code^{2 (3 h} US- 6,040,892 <u>A1</u> 03-21-2000 Pierrat US Ŭ3 ŪS-USus US US US-US-US-TIE ÜŠ US. US-US FOREIGN PATENT DOCUMENTS Examiner Initials Foreign Pubmit Dusament Name of Palentee or Pages, Critismus, Lines, Where Relevant Passe Applicant of Cited Document Date Or Relevant Figures Appear Country Code² Number ⁴ Niral Code² (Flavoure) Examinor
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